## CUSTOMER NO. 36257

## IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant:

Wayne Glenn Renken

Title:

System and Method for Heating and Cooling Wafer at Accelerated Rates

Application No.:

10/619,731

Filing Date:

July 15, 2003

Examiner:

Rakesh K. DHINGRA

Group Art Unit:

1763

Docket No.:

**SENS.007US1** 

Conf. No.:

7022

Mail Stop RCE Commissioner for Patents P.O. Box 1450 Alexandria, VA 22313-1450

## AMENDMENT ACCOMPANYING RCE AND STATEMENT OF INTERVIEW

Sir:

This is in response to the final Office Action dated December 19, 2005, and is being filed with a Request for Continued Examination. An appropriate request for extension of time accompanies this paper.

Amendments to the Specification are not being made.

Claim Amendments are reflected in the listing of claims, which begins on page 2 of this paper.

**Drawing Amendments** are not being made.

Remarks begin on page 8 of this paper.